

PATENT APPLICATION

Sheet 1 of 2

FORM PTO-1449 LIST OF PATENTS AND PUBLICATIONS FOR APPLICANT'S INFORMATION DISCLOSURE STATEMENT (Use several sheets if necessary)	ATTY. DOCKET NO.	APPLICATION NO.	CONFIRMATION NO.
	200309716-1	16/677539	
	APPLICANT		
	Michael Monroe t al.		
	FILING DATE	GROUP	
	H rewith	Unkn.	

REFERENCE DESIGNATION

U.S. PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	PUBLICATION DATE	NAME	Pages, Columns, Lines Where Relevant Passages or Figures Appear
De	1A	5,583,688	12/1996	Hornbeck	—
	1B	5,650,881	07/1997	Hornbeck	—
	1C	5,919,548	07/1999	Barron et al.	—
	1D	6,025,951	02/2000	Swart et al.	—
	1E	6,121,552	09/2000	Brosnihan et al.	—
	1F	6,396,368	05/2002	Chow et al.	—
	1G	6,440,766	08/2002	Clark	—
	1H	6,469,330	10/2002	Vigna et al.	—
	1I	6,480,320	11/2002	Nasiri	—
	1J	6,523,961	02/2003	Ilkov et al.	—
De	1K	20020039470	04/2002	Braun et al.	—

FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	PUBLICATION DATE	NAME OF PATENTEE OR APPLICANT	Pages/Columns/Lines Where Relevant Passages/Figures Appear	Check if Translation attached
De	1L	EP1093143	04/2001	Lucent Tech Inc.	—	—
	1M	JP2000314634	07/2001	Lucent Tech Inc.	—	—
	1N					
	1O					
	1P					

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, etc.)

De	1Q	J.H. Smith et al., "Material and Processing Issues for the Monolithic Integration of Microelectronics with Surface-Micromachined Polysilicon Sensors and Actuators" SPIE, October 1995, Pages 1-10.
De	1R	Oliver Brand, "CMOS-based MEMS/DTU PhD Course/Topics in Microelectronics", Physical Electronics Laboratory, ETH Zurich, http://www.iqe.ethz.ch/pel , slides A-2 through A-36.
De	1S	J.H. Smith et al., "Embedded Micromechanical Devices for the Monolithic Integration of MEMS with CMOS", 1995 IEEE, Pages 609-612.
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PATENT APPLICATION

Sheet 2 of 2

FORM PTO-1449 LIST OF PATENTS AND PUBLICATIONS FOR APPLICANT'S INFORMATION DISCLOSURE STATEMENT (Use several sheets if necessary)	ATTY. DOCKET NO.	APPLICATION NO.	CONFIRMATION NO.
	200312474-1		
	APPLICANT		
	Michael Monroe et al.		
	FLING DATE	GROUP	
	Herewith	Unkn.	

REFERENCE DESIGNATION

U.S. PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	PUBLICATION DATE	NAME	Pages, Columns, Lines Where Relevant Passages or Figures Appear
Dh	2A	20030034535	02/2003	Barenburg et al.	—
	2B	5,485,304	01/1996	Kaeriyama	—
	2C	5,631,782	05/1997	Smith et al.	—
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	2H				
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		DOCUMENT NUMBER	PUBLICATION DATE	NAME OF PATENTEE OR APPLICANT	Pages/Columns/Lines Where Relevant Passages/Figures Appear	Check if Translation attached
	2L					
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Dh	2Q	Bikram Baidya et al., "Layout Verification and Correction of CMOS-MEMS Layouts", Carnegie Mellon University, Pittsburgh.
Dh	2R	Jeffrey D. Zahn et al., "A Direct Plasma Etch Approach to High Aspect Ratio Polymer Micromachining With Applications in Biomems and CMOS-MEMS, 2002 IEEE, pgs. 137-140.
Dh	2S	Jim Hunter et al., "CMOS friendly MEMS manufacturing process", 1998 IEEE, pgs. 103-104.

EXAMINER

Dh

DATE CONSIDERED

Nov-04